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(71) Applicant: **ICHOR SYSTEMS, INC.** [US/US]; 3185 Laurelview Ct., Fremont, CA 94538 (US).

(72) Inventors: **CARSON, Stephen**; 177 Vandale Road, Woodstock, NY 12498 (US). **TREUR, Randolph**; 875 Mission St., San Luis Obispo, CA 94305 (US).

(74) Agent: **HERD, Matthew, E.**; The Belles Group, P.C., 1800 John F. Kennedy Boulevard, Suite 1010, Philadelphia, PA 19103 (US).

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(54) Title: SEAL RETAINER FOR A COMPONENT ASSEMBLY AND METHOD OF INSTALLING A COMPONENT INTO AN APPARATUS FOR CONTROLLING FLOW

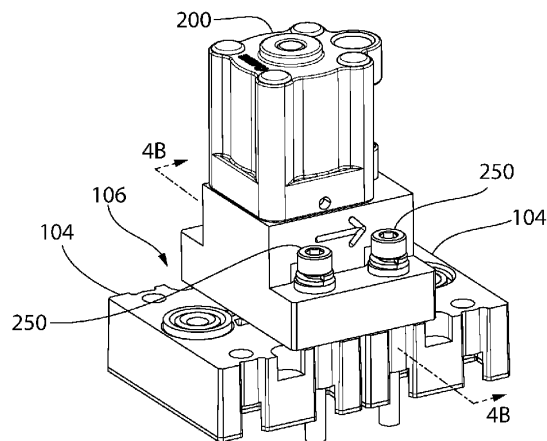


FIG. 4A

(57) Abstract: Apparatuses for controlling fluid flow are important components for delivering process fluids for semiconductor fabrication. These apparatuses for controlling fluid flow require a variety of fluid flow components which are tightly packaged within the apparatuses for controlling flow. Servicing the apparatuses requires specialized equipment and methods which enable installation of seals in close quarters in apparatuses which are installed in the field. Seal retainers may be used to retain the seals during assembly of fluid flow components into apparatus for controlling flow.

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